

## AMENDMENT TO THE SPECIFICATION

Please amend paragraph [0021] of the specification as follows:

[0021] Figure 6 shows a cross section of the holder detailing an individual mechanism in the overall array for securing an individual electrode in the holder assembly showing the configuration of the elements: face plate 71 and fastening screws 72 attaching to block or middle plate 46M and retainer or rear plate 73 with fastening screws 74. The substrate 46... is shown maintained in the column in the middle plate 102... which is concentrically aligned with opening 101... in the face plate. The spring 77 and electrode retainer 76 exert a force upon the electrode to secure the electrode at the spot area 80 at which the surface of the electrode is exposed to the plasma beam during the coating process. Small mask 75 in the opening 101... is at the base of a chamfer or bevel 71C in the opening 101... in faceplate 71. Thus the upper section of the electrode substrate 46... is inset into the face plate 71. A small oversize tolerance in the column 102... in middle plate 46M facilitates the insertion of the electrode. Large mask 90 overlays the face plate opening 101... Interior ring 202 divides column 102 into an upper section, receiving the electrode, and a rear section, receiving the spring retainer.